# Effect of Contaminant Particles on Folding of Encapsulating Organic-Inorganic Multilayer for Foldable OLEDs

# Yun Taek Park, Sang Woo Kim, Gui Young Han, Sung Min Cho

School of Chemical Engineering, Sungkyunkwan University, Korea Keywords: Thin film encapsulation, Folding, Particle

# ABSTRACT

The effect of contaminant particles on the folding of encapsulating organic-inorganic multilayer was investigat ed. The stability of the organic-inorganic multilayer thin fil ms was evaluated when they were folded inward or outw ard in 1 mm radius according to the size of the contamina nt particles and the thickness of the multilayer thin films. It was confirmed that the organic- inorganic multilayer films deposited by the atomic layer deposition and plasma-enh anced chemical vapor deposition methods completely cov ers the contaminant particles regardless of the size of the particles. However, due to the angle of curvature in the res ulting encapsulation structure caused by the presence of t he contaminant particles, higher stress is generated arou nd the particles and the cracking due to folding is more e asily occurred. In this study, we proposed the stability crit eria for the thickness of encapsulation layer upon folding even in the presence of contaminant particles

#### **1** INTRODUCTION

We have secured the stability of OLED devices by enc apsulation with thin film of organic / inorganic composite I ayer by vitex method. However, as the research of foldabl e display or rollable display becomes more active, the me chanical properties of encapsulation layer will be seriousl y deteriorated by contaminant particles, and it is time to id entify it. The objective of this study is to investigate the pa rticle coverage of the encapsulation thin film when the co ntaminant particles are present on the surface of the OLE D devices and to evaluate the effect of the covered particl es on folding of the encapsulation thin film. This study is v ery important in the implementation of foldable OLEDs an d ultimately aims to provide a criteria for stable thickness of thin film encapsulation for folding.

### 2 EXPERIMENT

This section describes the details about the text content of the manuscript. An Al<sub>2</sub>O<sub>3</sub> thin film grown by atomic layer deposition (ALD) was used as the thin film encapsulation I ayer for this study. The organic layer used in this study ca used plasma phenomenon by using n - hexane. The plas ma polymer layer fragments the organic material from the polymerization by-products of the radical. First, a 1- $\mu$ m-thick poly (methyl methacrylate) (PMMA) layer was sp in-coated onto a 50- $\mu$ m-thick polyimide (PI) substrate for

surface planarization. Since a poly (ethylene



Fig. 1. Folding condition (a) Schematic diagram of 1 mm diameter folding. (b) Photographic image of folding apparatus. Two folding plates are spaced  $\pi$  mm apart and designed to have a spacing of 2 mm at the folding. The sample is tightly attached to the PDMS surface on the folding plate during the folding.

terephthalate) substrate of the same thickness is damag ed by repetitive folding, we utilized a PI substrate causin g no damage under the same condition owing to the rel atively low Young's modulus. Polystyrene was used as contaminated particles, and diluted 1: 1000 with IPA. An d spin coating was carried out at 4000 RPM conditions f or application. Al<sub>2</sub>O<sub>3</sub> and plasma polymer layers were d eposited on the contaminated substrate by ALD and pla sma-enhanced chemical vapor deposition, respectively. For the deposition of the Al<sub>2</sub>O<sub>3</sub> layer, TMA and ozone we re used. Each precursor was injected into a deposition c hamber maintained at a pressure of  $3 \times 10$ 

 $^{-2}$  Torr for 2 s. After the injection of each precursor, the chamber was purged for 10 s using argon (Ar) gas. The substrate temperature was maintained at 90 °C and the Al<sub>2</sub>O<sub>3</sub> growth rate per cycle was 1.2 Å. The plasma poly mer layer was deposited in Ar plasma using n- hexane a nd the deposition rate was 20 nm/min. The water vapor transmission rate (WVTR) of the fabricated encapsulati on layers was measured by the Ca test. The measured WVTRs of contaminated 10 dyad multilayer (1

dyad: 5-nmthick Al<sub>2</sub>O<sub>3</sub> layer and 20-nm-thick organic layer) was 7  $\times$  10^{-4} gm^{-2} day^{-1}, respectively. Here, the Al\_2O\_3 layer grown by ALD has excellent moisture resistance, whereas the plasma polymer has poor moisture resistance and thus does not significantly affect the WVTR. Therefore, the thi ckness of the Al<sub>2</sub>O<sub>3</sub> layer was fixed at 50 nm, and the foldi ng stabilities of the inorganic single layer and organic- ino rganic multilayer with the same total thickness of the Al<sub>2</sub>O 3 layer were evaluated. However, in the case of the organi c-inorganic multilayer barrier, a lower WVTR is usually ob tained because the path of the moisture penetrating throu gh the defects becomes tortuous. Nevertheless, it was co nfirmed by the WVTR ( $8 \times 10^{-4}$  gm

<sup>-2</sup> day<sup>-1</sup>) that the barrier properties were maintained when 1R folding was performed after contaminant particles were applied. In addition, the side state was checked by using a Focused Ion Beam (FIB) to check whether the barrier was broken during 1R folding in the presence of contaminant particles.

#### RESULTS 3

In this paper, we can recognize thin film encapsulation f or stable foldable OLED display is advantageous as the th ickness of encapsulation layer is thinner. If contaminant p articles are present in the foldable OLED display, when th e encapsulation layer is thick, it can cover the particles suf ficiently and be stable even when folded. On the other han d, if the thickness of the encapsulation layer is very thin, the contaminant particles may not be covered enough, encap sulation layer crack due to folding. As the structure of the organic-inorganic multilayer encapsulation layer, a structur e in which 5nm Al<sub>2</sub>O<sub>3</sub> inorganic layer and 60nm plasma po lymer layer was alternately stacked 10 dyads was always stable to 1R folding.



Fig. 2. (a) Schematic diagram representing 100% step coverage of an encapsulating thin film (thickness t) onto a particle (diameter d); (b) cross-sectional SEM images . of particles encapsulated with organic-inorganic multil ayer thin film.

If the organic-inorganic multilayer encapsulation layer with a total thickness of (t) completely covers 100% of sp herical contaminant particles with diameter (d), it must

have a covering angle as shown in Fig 2 (a). In fact, the organic-inorganic multilayer encapsulation layer was de posited on spherical particles having a diameter of 5,1 a nd 0.1 µm, and the coating angles were found to be in c lose agreement with the expected coating angles. The I arger the size of the contaminated particles, the lower th e coating angle, and in the case of in-folding folding tow ard the top of the particles, cracking is most likely from t he periphery of the polluted particle with the lowest coati ng angle. Therefore, the occurrence of cracking by foldi ng is expected to depend on the size (d) of the contami nant particles and the thickness (t) of the encapsulation film. The effect of contaminant particles on the crack for mation of the encapsulation film was investigated when the contaminant particles were present in the fold.





Fig. 3. (a) Cross-sectional SEM image showing around a contaminant particle before 1R in-folding. (b) Crosssectional SEM image showing a crack originated from a perimeter position around a contaminant particle a fter 1R in-folding.

Fig. 3 is a SEM photograph of cracks generated after 1R repeated folding after depositing spherical particles having a diameter of 2 µm by depositing 5 nm Al<sub>2</sub>O<sub>3</sub> inor ganic thin film and 60 nm plasma polymer thin film alter nately. The total thickness of this organic-inorganic multi layer encapsulation thin film structure is 590 nm. Calcul ating the cover angle using the equation shown in Figur e 2 shows that it is about 75°. The actual measured coat ing angle was about 82°, and it was confirmed that the c rack occurred in the circumference of the polluted particl e with the steepest coating angle when 1R in- folding fol ding occurred at the coating angle.

Fig. 4 is a SEM photograph of cracks generated after 1R repeated folding after depositing spherical particles having a diameter of 2 µm by depositing 8 µm planarizat ion layer by PECVD. After planarization layer,

deposited encapsulation a structure in which 5nm Al<sub>2</sub>O<sub>3</sub> inorganic layer and 60nm plasma polymer layer was alt ernately stacked 10 dyads. The total thickness of this or ganic-inorganic multilayer encapsulation thin film structu re is 8590 nm. Calculating the cover angle using the eq uation shown in Figure 2 shows that it is about 141°. Th e actual measured coating angle was about 146°. After 1R folding, it can't find crack around contaminant particl es.



Fig. 4. Cross-sectional SEM image showing a contam inant particle with planarization layer after 1R in-foldi ng

#### 4 DISCUSSION

In fact, there is a possibility that large contaminant part icles are generated in the manufacturing process of OLE D display, and if the large contaminant particles exist on t he surface before the thin film encapsulation process, the surface is flattened before the thin film encapsulation to minimize the occurrence of cracks in the repeated folding process. It is necessary to loosen the surface coating an gle of the thin film to 140° or more by performing the proc edure.



Fig. 5. 1R folding stability of organic-inorganic multila yer encapsulation structure when contaminant particl es exist on the folding surface.

As shown in Fig. 10, when the coating angle was more than 140°, it was found to be stable to 1R in-folding folding.

## 5 CONCLUSIONS

From the above results, organic-inorganic multilayer encapsulation layer deposited by ALD and PECVD is conf irmed that the coating uniformity of contaminant particles i s about 100%. When contaminant particles are present a nd folding occurs, cracks are generated near the perimet er of the contaminant particle. The occurrence of cracks is closely related to the covering angle, which can occur more often in-folding than out-folding. If the coating angle was looser than about 140°, it was found to be sta ble even for folding in 1R. Even if there are contaminant particles, it is very important to planarization before depo sited thin film encapsulation layer so that the coating an gle is loosened to more than 140° around particles. This research is looking forward to be used not only for the fo Idable OLED display under development but also for the encapsulation layer for rollable or stretchable OLED dis play.

## REFERENCES

- Y. C. Han, E. G. Jeong, H. Kim, S. Kwon, H. G. Im, B. S. Bae, K. C. Choi, Reliable thin-film encapsulati on of flexible OLEDs and enhancing their bending c haracteristics through mechanical analysis, RSC A dv. 6, pp. 40835-40843 (2016).
- 2 J. Lewis, Material challenge for flexible organic devi ces, Mater. Today 9, pp. 38-45 (2006).
- 3 S. Kim, H.-J. Kwon, S. Lee, H. Shim, Y. Chun, W. Choi, J. Kwack, D. Han, M. S. Song, S. Kim, S. Mohamm adi, I. S. Kee, S. Y. Lee, Low-power flexible organic light-emitting diode display device, Adv. Mater. 23, pp. (2011) 3511-3516.
- 4 B. Hwang. S. Lim, M. Park, S. M. Han, Neutral plane control by using polymer/graphene flake composites f or flexible displays, RSC Adv. 7, pp. 8186-8191 (201 7).
- 5 S.-W. Seo, H. Chae, S. J. Seo, H. K. Chung, S. M. C ho, Extremely bendable thin-film encapsulation of or ganic light-emitting diodes, Appl. Phys. Lett. 102, pp. 161908 (2013).
- 6 P. F. Carcia, R. S. McLean, M. H. Reilly, M. D. Groner, S. M. George, Ca test of Al2O3 gas diffusion barrie rs grown by atomic layer deposition on polymers, A ppl. Phys. Lett. 89, pp. 031915 (2006)
- 7 M.-H. Park, J.-Y. Kim, T.-H. Han, T.-S. Kim, H. Kim, T.-W. Lee, Flexible lamination encapsulation, Adv. M ater. 27, pp. 4308-4314 (2015).
- 8 S. Li, Y. Su, R. Li, Splitting of the neutral mechanical plane depends on the length of the multilayer structur e of flexible electronics, Proc. R. Soc. A. 472, pp. 201 60087 (2016).
- 9 Z. Suo, E. Y. Ma, H. Glexkova, S. Wagner, Mechanics of rollable and foldable film-on-foil electronics, Appl. Phys. Lett. 74, pp. 1177-1179 (1999).
- 10 C.-C. Lee, Y.-S. Shih, C.-S. Wu, C.-H. Tsai, S.-T. Y eh, Y.-H. Peng, K.-J. Chen, Development of robust f lexible OLED encapsulations using simulated estim ations and experimental validations, J. Phys. D: Ap pl. Phys. 45, pp. 275102 (2012).
- 11 Y.-F. Niu, S.-F. Liu, J.-Y. Chiou, C.-Y. Huang, Y.-W. Chiu, M.-H. Lai, Y.-W. Liu, Improving the flexibility of AMOLED display through modulating thickness of I ayer stack structure, J. SID 24, pp. 293-298 (2016).

- 12 H. Lee, J. Han, S. B. Ham, C. Jang, M. S. Huh, S. M. Cho, Folding stabilities of encapsulation layers at posi tions off the mechanical neutral plane, Appl. Phys. Exp ress 11, pp. 086502 (2018).
- 13 W. Kim, I. Lee, D. Y. Kim, Y.-Y. Yu, H.-Y. Jung, S. K won, W. S. Park, T.-S. Kim, Controlled multiple neutr al planes by low elastic modulus adhesive for flexible organic photovoltaics, Nanotechnology 28, pp. 19400 2 (2017).
- 14 J. H. Kwon, Y. Jeon, S. Choi, J. W. Park, H. Kim, K. C.

Choi, Functional design of highly robust and flexible thin-film encapsulation composed of quasi-perfect s ublayers for transparent, flexible displays, ACS Ap pl. Mater. Interfaces 9, pp. 43983-43992 (2017).

[15] S. H. Jen, J. A. Bertrand, S. M. George, Critical ten sile and compressive strains for cracking of Al2O3 f ilms grown by atomic layer deposition, Appl. Phys. Lett. 101, pp. 234103 (2012).